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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/685,938	10/15/2003	Yee-Chia Yeo	TSM03-0926	7692
43859	7590	05/04/2005	EXAMINER	
SLATER & MATSIL, L.L.P. 17950 PRESTON ROAD, SUITE 1000 DALLAS, TX 75252			FARAHANI, DANA	
			ART UNIT	PAPER NUMBER
			2891	

DATE MAILED: 05/04/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

**Office Action Summary**

Application No.

10/685,938

Applicant(s)

WANG

Examiner

Dana Farahani

Art Unit

2891

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

**Period for Reply**

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

**Status**

- 1) ☒ Responsive to communication(s) filed on 08 April 2005.
- 2a) ☐ This action is FINAL. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

**Disposition of Claims**

- 4) ☒ Claim(s) 1-19 is/are pending in the application.
- 4a) Of the above claim(s) \_\_\_\_\_ is/are withdrawn from consideration.
- 5) ☐ Claim(s) \_\_\_\_\_ is/are allowed.
- 6) ☒ Claim(s) 1-19 is/are rejected.
- 7) ☐ Claim(s) \_\_\_\_\_ is/are objected to.
- 8) ☐ Claim(s) \_\_\_\_\_ are subject to restriction and/or election requirement.

**Application Papers**

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on \_\_\_\_\_ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.  
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).  
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

**Priority under 35 U.S.C. § 119**

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some \* c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

\* See the attached detailed Office action for a list of the certified copies not received.

**Attachment(s)**

- 1) ☒ Notice of References Cited (PTO-892)
- 2) ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
- 3) ☐ Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)  
Paper No(s)/Mail Date \_\_\_\_\_
- 4) ☐ Interview Summary (PTO-413)  
Paper No(s)/Mail Date. \_\_\_\_\_
- 5) ☐ Notice of Informal Patent Application (PTO-152)
- 6) ☐ Other: \_\_\_\_\_

**DETAILED ACTION**

*Election/Restrictions*

1. Applicant's election without traverse of claims 1-19 in the reply filed on 4/8/05 is acknowledged.

*Claim Rejections - 35 USC § 102*

2. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

3. Claims 1, 2, 4, 5, 9, 11, and 12-16 are rejected under 35 U.S.C. 102(e) as being anticipated by Umebayashi (US Patent Application Publication 2003/0011032), hereinafter '032 reference.

Regarding claims 1, 2, 9, and 13, the '032 reference discloses in figure 5A, a semiconductor chip comprising:

a semiconductor substrate comprising an active region (all of the horizontal surface beneath and between the isolation regions 12 of figure 3A);

a first transistor structure 71 (the left gate of the plurality of gates which are numbered 71) formed in/on the active region, the first structure having source and drain 74, and its gate is fully silicided by the silicide 75;

and

at least one dummy silicide structure (the dummy silicided gate 71, the right gate of the plurality of gates numbered 71 in the figure).

Regarding claims 4 and 15, the dummy silicide region is located in the active region.

Regarding claims 5 and 16, the dummy structure is located in an isolation region separate from the active region (note that "in" is defined as location, or position within limits).

Regarding claim 11, the '032 reference discloses an etch stop layer, 25 of figure 8, overlying portions of the first structure.

Regarding claim 12, a dielectric layer 18 overlies the first structure and the dummy silicide structure.

Regarding claim 14, electrical contacts 84 and 87, of figures 7B and 8, respectively, are coupled to the respective gate, source, and the drain regions.

### *Claim Rejections - 35 USC § 103*

4. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

5. Claim 3 is rejected under 35 U.S.C. 103(a) as being unpatentable over the '032 reference as applied to claim 2 above, and further in view of Yu (US Patent 6,686,248).

The '032 reference discloses the claimed invention, as discussed above, except for a gate dielectric comprising a high permittivity dielectric selected from the group consisting of aluminum oxide, hafnium oxide and such.

Yu discloses that these materials are used as high dielectric constant material of a gate dielectric. Therefore, it would have been obvious to one of ordinary in the art at the time of the invention to use these materials as the gate dielectric of the '032 reference since it was known in the art that high dielectric constant materials are used as gate electrodes. See *In re Leshin*, 125 USPQ 416, for the proposition that it is within the general skill of a worker in the art to select a known material on the basis of its suitability for the intended use.

6. Claims 6, 7, 17 and 18 are rejected under 35 U.S.C. 103(a) as being unpatentable over the '032 reference as applied to claim 1 above, and further in view of Paton et al., hereinafter Paton (US Patent 6,873,051).

The '032 reference discloses the claimed invention, as discussed above, except for the dummy silicide structure is nickel silicide.

Paton discloses nickel silicide in a gate silicide structure offers advantages such as low temperature formation (see column 1, lines 45-48). Therefore, it would have been obvious to one of ordinary in the art at the time of the invention to use Nickel silicide as the silicide layer of the '032 reference since the advantages of using Nickel as a gate silicide were known in the art. See *In re Leshin*, 125 USPQ 416, for the proposition that it is within the general skill of a worker in the art to select a known material on the basis of its suitability for the intended use.

7. Claims 8 and 19 are rejected under 35 U.S.C. 103(a) as being unpatentable over the '032 reference, as applied to claim 1 above, and further in view of Holmes et al., hereinafter Holmes (US Patent 6,797,641).

The '032 reference discloses the claimed invention, as discussed above, except for the dummy silicide structure comprises germanium.

Holmes discloses a gate structure comprises germanium silicide (see column 2, lines 14-22), further disclosing this gate structure improves reliability of the gate structure (see column 1). Therefore, it would have been obvious to one of ordinary in the art at the time of the invention to use germanium in the structure of the gates of the '032 reference to improve the reliability of the DRAM structure therein. See *In re Leshin*, 125 USPQ 416, for the proposition that it is within the general skill of a worker in the art to select a known material on the basis of its suitability for the intended use

8. Claim 10 is rejected under 35 U.S.C. 103(a) as being unpatentable over the '032 reference as applied to claim 1 above, and further in view of Darmawan et al., hereinafter Darmawan (US Patent 5,994,759).

The '032 reference discloses the claimed invention, as discussed above, except for the substrate is a semiconductor-on-insulator (SOI) substrate.

Darmawan discloses advantages associated with a SOI substrate, versus a non-SOI substrate. These advantages include parasitic capacitance reduction and improved device isolation (see column 1, lines 15-20). Therefore, it would have been obvious to one of ordinary in the art at the time of the invention to use a SOI structure in the structure of the '032 reference to benefit from the advantages associated with the SOI structures, as mentioned above.

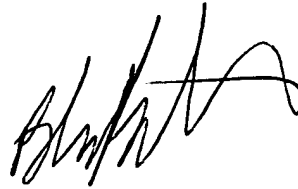
### ***Conclusion***

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Dana Farahani whose telephone number is (571)272-1706. The examiner can normally be reached on M-F 9:00AM - 5:00PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Bill Baumeister can be reached on (571)272-1722. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

D. Farahani



**B. WILLIAM BAUMEISTER  
SUPERVISORY PATENT EXAMINER**